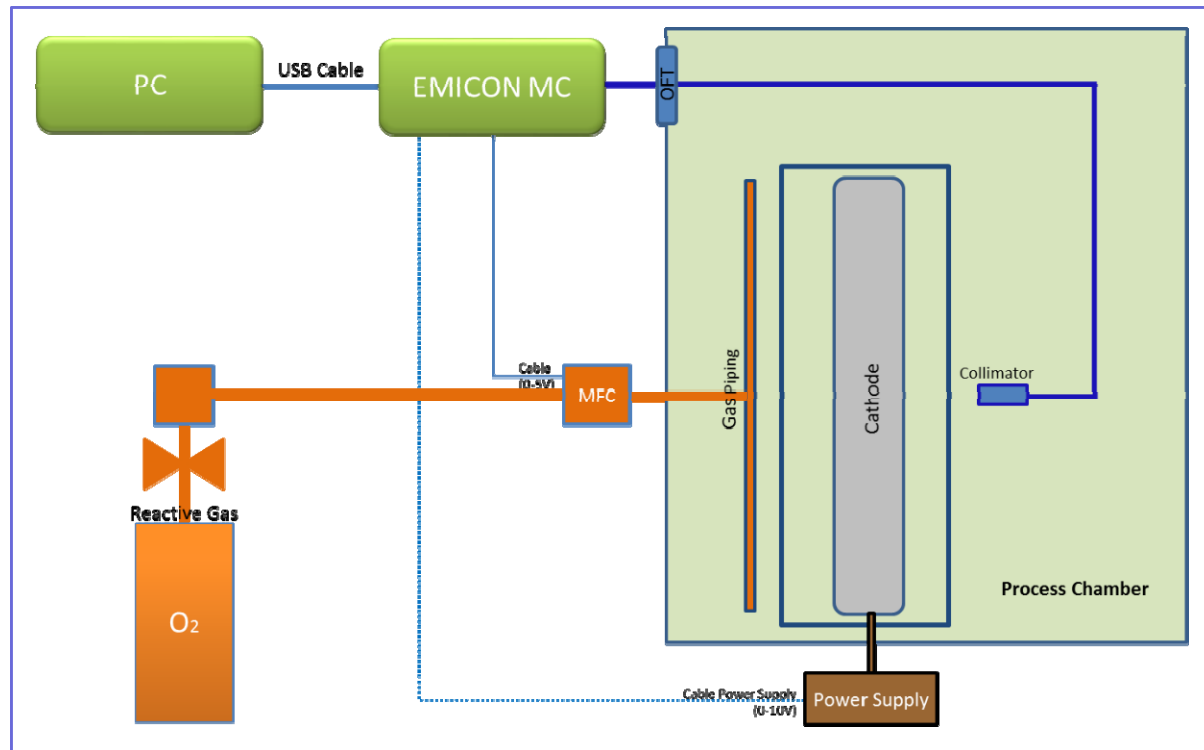


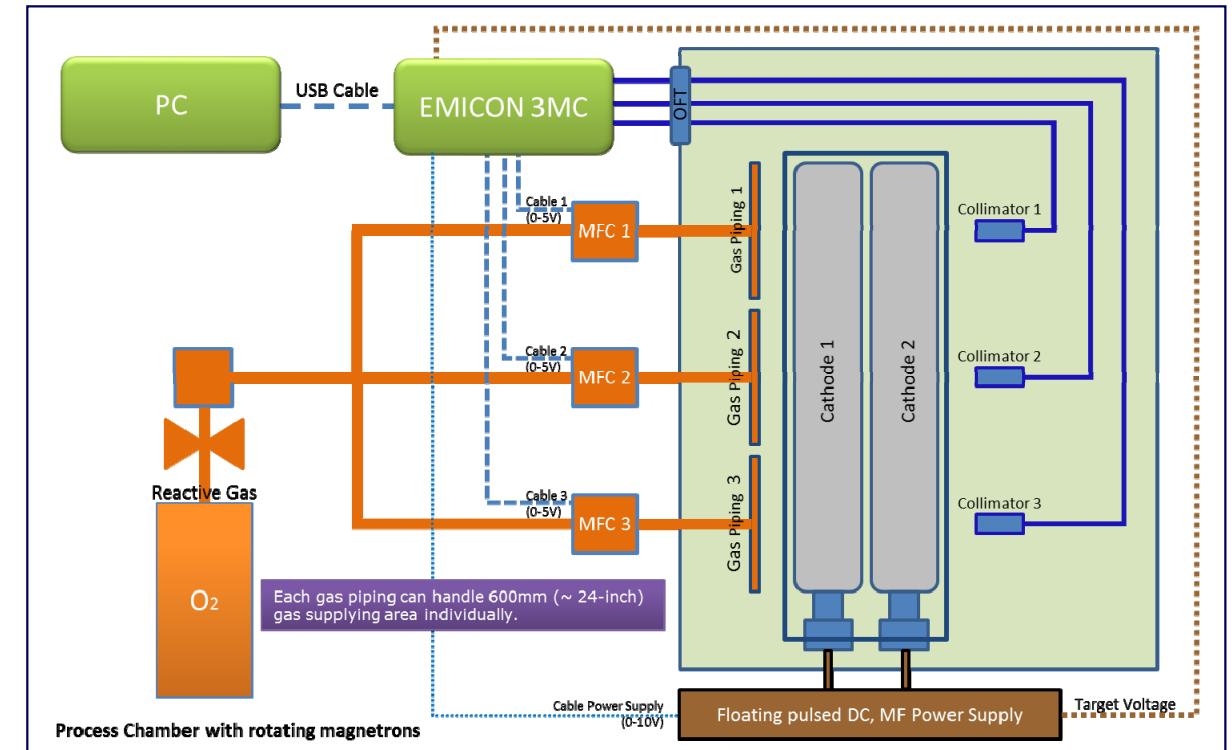
Reactive Sputtering Processes

General setup

EMICON single-channel setup



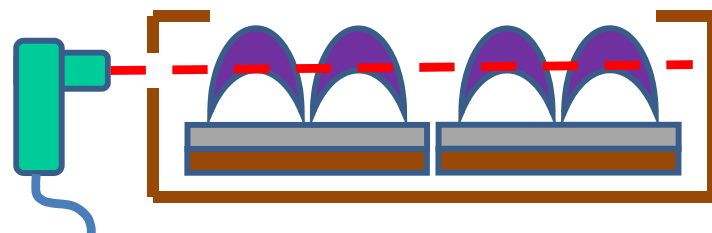
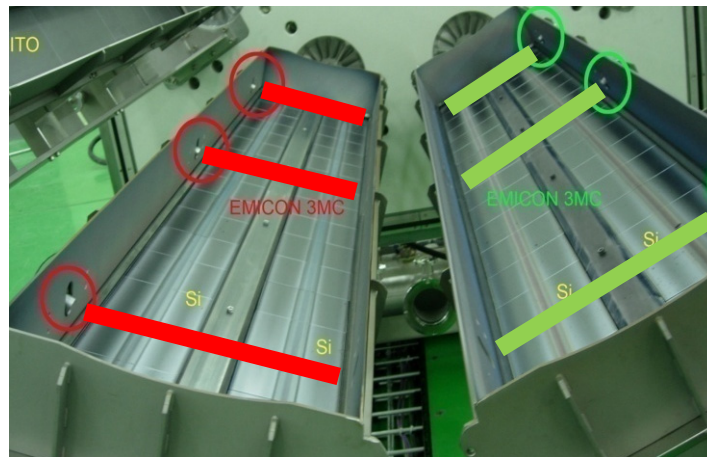
EMICON multi-channel setup



Reactive Sputtering Processes

Optics setup

Magnetron targets



Important:

All light along the line-of sight is detected!

Alignment rules:

- Line-of-sight through similar plasma regions
- Line-of-sight above process surface
- Line-of-sight parallel to process surface

